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12/18/01

U.S.

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

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| APPL NUM 10025144 | FILING DATE 12/18/2001 | CLASS 438 | SUBCLASS 633 | GAU 2813 | EXAMINER <i>Smoot</i> |
| APPLICANTS: Moon Yongsik; Mai David; Wijekoon Kapile; Bajaj Rajeev; Surana Rajul; Hu Yongqi; Kaushal Tony; Li Shijian; Li Jui-Lung; Wang Shi-Ping; Lam Gary; Radeker Fred; | | | | | |
| CONTINUING DATA VERIFIED: <i>S.W.S.</i> THIS APPLN CLAIMS BENEFIT OF 60/304,543 07/11/2001 | | | | | |
| FOREIGN APPLICATIONS VERIFIED: <i>None S.W.S.</i> | | | | | |
| PG-PUB DO NOT PUBLISH <input type="checkbox"/> | | | RESCIND <input type="checkbox"/> | | |
| Foreign priority claimed <input type="checkbox"/> | | | ATTORNEY DOCKET NO | | |
| 35 USC 119 conditions met <input type="checkbox"/> | | | AMAT/5803/CMP/CMP/RKK | | |
| Verified and Acknowledged Examiner's initials <i>S.W.S.</i> | | | | | |
| TITLE: Method and apparatus for polishing metal and dielectric substrate | | | | | |

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NOTICE OF ALLOWANCE MAILING DATE: *7/29/03*

ISSUE FEE

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| <i>\$1600</i> | |

☐ TERMINAL DISCLOSURE

| DRAWINGS | | | CLAIMS ALLOWED | |
|--------------|-------------|------------|----------------------------|----------------------|
| Sheets Drwg. | Figs. Drwg. | Print Fig. | Total Claims | Print Claim for O.G. |
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| | | | ISSUE BATCH NUMBER | |

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|------------------------------|--------|
| (Assistant Examiner) | (Date) |
| (Primary Examiner) | (Date) |
| (Legal Instruments Examiner) | (Date) |